



an Open Access Journal by MDPI

Micro/Nano Photonic Devices and Systems

Guest Editors:

Prof. Dr. Pei-Cheng Ku

EECS Department, University of
Michigan, 1301 Beal Ave, Ann
Arbor, MI 48109, USA

Prof. Dr. Jaeyoun Kim

Department of Electrical &
Computer Engineering, Iowa
State University, Ames, IA 50011,
USA

Deadline for manuscript
submissions:

closed (29 February 2016)

Message from the Guest Editors

Dear Colleagues,

This Special Issue seeks reviews, regular research papers, and short communications on the advances in the science and technologies that enable the miniaturization of photonic devices and systems. Areas of interest include, but are not limited to, novel fabrication techniques, materials synthesis, optical properties of nano and micro structures and materials, novel device structures or concepts, new insights into device/system design, modeling, and characterization, device/system actuation and tuning, packaging and integration, and the innovative use of miniaturized photonic devices and systems in applications including, but are not limited to, sensing, display and imaging, energy conversion, optofluidics, data storage, communication, microscopy, spectroscopy, optical MEMS, and quantum information processing.

Prof. Dr. Pei-Cheng Ku

Prof. Dr. Jaeyoun (Jay) Kim

Guest Editors





an Open Access Journal by MDPI

Editor-in-Chief

Prof. Dr. Nam-Trung Nguyen

Queensland Quantum and
Advanced Technologies Research
Institute, Griffith University, West
Creek Road, Nathan, QLD 4111,
Australia

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Contact Us

Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
[X@micromach_mdpi](https://twitter.com/micromach_mdpi)